# **CMOS** Compatible Lateral Bipolar Transistor for BiCMOS Technology

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A CMOS-compatible lateral bipolar transistor having neither an epitaxial layer nor n'buried layers is proposed as a result the following investigation. A BiCMOS gate delay is not influenced greatly by the base width,  $W_B$  (i.e. by  $f_T$ , since  $f_T \propto 1/W_B^2$ ) because of a large injection of minority carriers. Therefore low  $f_T$  (low cost) bipolar transistors can be useful for BiCMOS gate circuits. The obtained values of  $h_{fe}, f_{Tmax}$  and  $r_{bb}$  are 40, 2.3 GHz and 99  $\Omega$ , respectively.

### 1. Introduction

Recently, the drive to increase the speed performance of computers has accelerated the importance of high-speed, large-scale memories. BiCMOS technologies are very promising for this application since they offer the high drive capabilities of bipolar transistors while retaining the inherent low power consumption and high level of packaging density provided by CMOS. (1) (2) Most existing BiCMOS processes, however, make use of a high performance vertical bipolar transistor which results in a rather complex and high cost process due to the incompatibility of the two types of transistors. The high performance vertical bipolar transistors used for BiCMOS LSIs require n' buried layers and an epitaxial silicon layer.

Usually, the speed performance of bipolar transistors is estimated by the  $f_{\tau}-I_{\circ}$ characteristic. Therefore high  $f_{\tau}$  transistors are regarded as necessary for high speed BiCMOS LSIs. The authors have noticed, however, that  $f_{\tau}$  does not have a great effect on BiCMOS gate delay time. This paper describes the investigation by computer simulation of factors which influence the delay time in BiCMOS gate circuits. In accordance with the above investigation, a new lateral bipolar transistor for a BiCMOS gate having neither n<sup>+</sup> buried layers nor an epitaxial silicon layer is proposed and is actually fabricated. Some properties of the bipolar transistor are also reported.

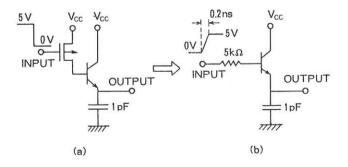


Fig. 1. (a) BiCMOS gate circuit, and (b) its equivalent circuit for computer simulation.

2. Proposal of a new lateral bipolar transistor for BiCMOS gates

2.1 Essential factors of BiCMOS gate delay It has been determined by experiment that BiCMOS gate delay, tpd can be improved when the thickness of the epitaxial silicon layer, depi is decreased. First, the dependence of bipolar transistor properties and tpd on depi are investigated by computer simulation (transient analysis).

The equivalent circuit of a BiCMOS gate for simulation is shown in Fig.1. The MOS transistor of the BiCMOS gate is replaced with a 5 k $\Omega$  resistor in the equivalent circuit. It is assumed that the input voltage has a 0.2 ns delay.

Figure 2 shows the simulated  $f_T - I_c$ characteristics and the simulated dependence of Is, and Is on time for various depi. Moreover. the simulated dependence of maximum cutoff frequency, frmax, maximum emitter current, IEERAX and trd on deri is shown in Fig.3. Here  $t_{pd}$  is defined as the time during which output voltage rises from 0 V to 4.5 V. The thinner depi is, the shorter the distance between emitter and collector, d<sub>B-c</sub>, and consequently the depletion layer of the collector region also becomes thin. Thus fr becomes large when depi is decreased. The electric field intensity between emitter and collector also increases. Therefore Is increases when depi is decreased, and consequently tpd is improved.

Next, the relation between  $t_{p,q}$  and base width, W<sub>B</sub> is investigated. Figure 4 shows the simulated dependence of  $t_{pd}$  and  $f_{Tmax}$  on  $\mathtt{W}_{\mathtt{B}}$  . It is well known that high speed bipolar transistors usually have high freax. Conversely, as WB becomes small, freak increases abruptly, while t<sub>pd</sub> increases slightly in the BiCMOS gate circuit. The reason for this is described as follows.

In BiCMOS gate circuits, the basevoltage changes from 0 to +5 V or +5 to 0 V, depending on the input voltage. Therefore a high-level injection of minority carriers occurs from emitter to base. In such a case, the depletion layer of the collector region is distinguished by the injection of a large number of minority carriers. As a result, effective base width, WB( off) determined by carrier concen-tration is widened by the increase of carrier concentration at the base-collector junction, as shown in Fig. 5(a). Thus tpd does not depend very much on W<sub>B</sub>, determined by impurity concentration, while it does depend on Wa(off) in highlevel injection.

On the other hand,  $f_r$  is measured with a small signal circuit and therefore a highlevel injection does not occur, as shown in Fig.5(b). Consequently,  $f_r$  is approximately in proportion to  $1/W_B^2$ , and increases rapidly as  $W_B$  is decreased.

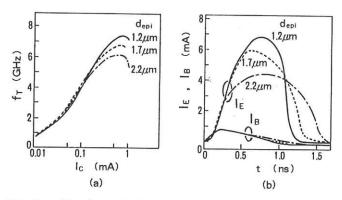


Fig. 2. Simulated f<sub>T</sub>-I<sub>c</sub> characteristics, and
(b) simulated dependence of I<sub>B</sub>, and I<sub>B</sub>
on time for various d<sub>epi</sub>.

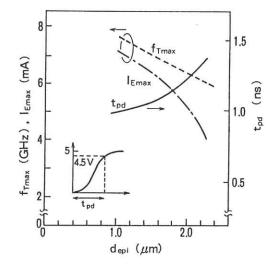


Fig. 3. Simulated dependence of  $f_{TDEX}$ ,  $I_{BDEX}$ and  $t_{pd}$  on  $d_{epi}$ .

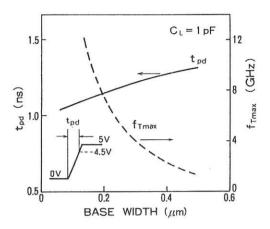


Fig. 4. Simulated dependence of  $t_{pd}$  and  $f_{TBAX}$ on base width,  $W_B$ .

# 2.2 CMOS-compatible lateral bipolar transistor

It is found that the depletion layer of the collector region is distinguished by the high-level injection of minority carriers in the BiCMOS gate circuits, and consequently tpd is dependent on WB(eff) (nearly equal to  $d_{\mathbf{g}-c}$ ). This suggests that it is possible to get high speed BiCMOS gate circuits even if lateral bipolar transistors are used. provided that the distance between emitter and collector is shortened by fine patterning technology. Therefore the authors propose that for BiCMOS gates, the CMOScompatible lateral bipolar transistor be utilized, since it has neither an epitaxial layer nor n' buried layers. The structure of the transistor is shown in Fig. 6.

The self-alinged emitter/collector of the transistor are simultaneously formed by implantation similarly to self-alinged source/drain in MOSFET. Poly-silicon placed between emitter and collector is used as a base electrode. Low base resistance can be achieved by this structure. The width of p' base is nearly equal to that of a LDD spacer. The ncollector of a vertical bipolar transistor is replaced by the pbase. The p base and PWELL of NMOS are simultaneously formed by implantation.

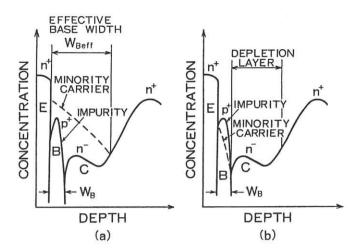


Fig. 5. Impurity and minority carrier profiles in case of (a) high-level injection, and (b) low-level injection.

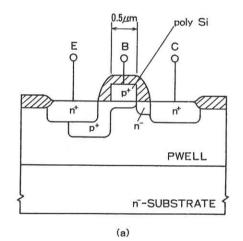


Fig. 6. Cross-sectional view of the CMOScompatible lateral bipolar transistor.

# 2.3 Bipolar transistor characteristics

Figure 7(a) shows the I-V characteristics of the lateral bipolar transistor. The Gummel plot of the same device is shown in Fig.7(b), which indicates that  $h_{\rm f}$ . is 188 ( $I_c = 100 \mu A$ ), 40 ( $I_c = 1 m A$ ).

 $BV_{CBO}$ ,  $BV_{CBO}$ , and  $BV_{BBO}$  are about 7, 6, and 6 V, respectively.  $BV_{CBO}$ ,  $BV_{CBO}$  are almost same, since  $BV_{CBO}$  is determined by the base-collector junction breakdown voltage in the lateral bipolar transistor.

The  $f_{\tau}-I_c$  characteristics are shown in Fig.8 which indicates that  $f_{\tau\,\text{max}}$  is 2.3 GHz at  $I_c=3$  mA. The obtained value of  $r_{\text{b},\text{b}}$  is 99  $\Omega$ .

# 3. Conclusion

It is found that delay time,  $t_{pd}$  does not depend very much on the base width  $W_B$ (and hence on  $f_T$ , since  $f_T \ 1/W_B^2$ ), determined by impurity concentration in BiCMOS gate circuits. This is because the depletion layer of the collector region is distinguished by the high-level injection of minority carriers. Consequently,  $t_{pd}$  is dependent on the effective base width,  $W_B(eff)$  (nearly equal to the distance between emitter and collector,  $d_{B-C}$ ).

This result suggests that it is possible to achieve high speed BiCMOS gate circuits even if lateral bipolar transistors are used. provided that dg.c is shortened by fine patterning technology. Therefore the CMOScompatible lateral bipolar transistor having neither an epitaxial layer nor n\* buried layers is proposed and is actually fabricated.

The obtained values of  $h_{fo}$ ,  $f_{Toax}$  and  $r_{bb}$  are 40, 2.3 GHz, and 99  $\Omega$ , respectively.

The lateral bipolar transistor proposed in this paper should be useful for low-cost, high-speed BiCMOS gate circuits.

#### Acknoledgments

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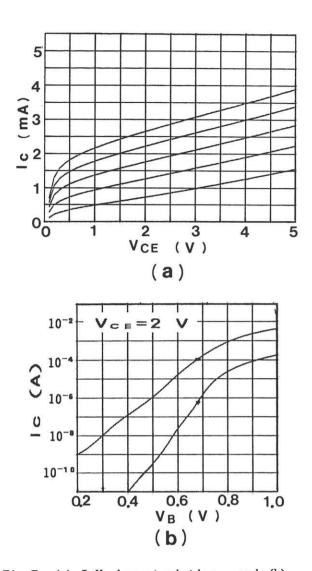


Fig. 7. (a) I-V characteristics, and (b) Gummel plot of the CMOS-compatible lateral bipolar transistor.

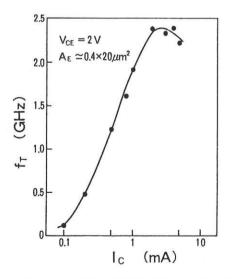


Fig. 8.  $f_{\tau} - I_c$  characteristics of the CMOScompatible lateral bipolar transistor.